

**IN THE SPECIFICATION**

Please replace the paragraph at page 9, lines 10-16, with the following:

- While the system disclosed herein illustrates a normal application of a beam to the specimen 110, it is to be understood that the teachings of the current invention contemplate application of a beam to a specimen in non-normal or oblique angles. As used herein, the term "retro" or "retro beam" is intended to cover both normal and non-normal reflection of the beam from the specimen, and therefore may include darkfield or brightfield techniques.

B1  
In the mechanization of Fig. 1, after the split beam contacts the specimen surface, the light scattered at a narrow angle to the incident beam from surface defects is collected in the Dark Field Narrow (DFN) channel, while most of the light scattered at larger angles by the surface defects is collected in the Dark Field Wide (DFW) channel. The remainder of the beam is specularly reflected back through the components outlined above. As two beams illuminate the wafer surface, two beams are returned through the elements up to the birefringent prism, which combines the two retro beams into a single beam. The single beam is returned through the remaining elements. This mechanization therefore forms a darkfield collection arrangement in the embodiment shown.

**IN THE CLAIMS:**

Please amend claim 1 as follows:

- B2
1. (Amended) A system for inspecting a specimen, comprising:  
[a light generating device;]  
an optical element arrangement for receiving light from [said] a light generating device and imparting light toward said specimen and receiving a retro beam from said specimen;  
a retro beam diversion element for diverting the retro beam from said optical element arrangement; and  
a multi-element sensing device for receiving and sensing retro beam position upon diversion from said optical element arrangement, [said sensing device having dimensions and an orientation to favorably receive said retro beam based on a predetermined expected diversion thereof] said multi-element sensing device comprising more than two linearly oriented sensing components.

Sub  
PC1

Please amend claim 24 as follows:

24. (Amended) A system for detecting contours on a specimen surface, comprising:

B3

application means for applying light energy to said specimen surface, said application means comprising a light generating device and an optical element arrangement for receiving light from said light generating device and imparting light toward said specimen surface; and

detecting means for detecting surface variations having relative surface height variations of less than approximately 1000 nanometers and surface contours over areas larger than particles and scratches, said detecting means comprising an optical relay for transmitting light energy received from said specimen surface and receiving a retro beam deflected therefrom and transmitting said retro beam toward a predetermined target.

Please cancel claim 25.

In claim 28, line 1, please replace "25" with -24--.

Sub  
PC3

Please amend claim 37 as follows:

B4

37. (Amended) A method for inspecting a specimen, comprising the steps of:  
[imparting light energy toward an arrangement of optical elements;]  
providing light energy to said specimen via an arrangement of optical elements, thereby creating a retro beam reflected from said specimen;  
passing said retro beam back through said arrangement of optical elements; and  
providing said retro beam to a multi-element sensing device, said retro beam having an expected diversion in a substantially predetermined direction and [said sensing device being substantially linearly dimensioned and oriented to receive diversions of said retro beam in said substantially predetermined direction] said multi-element sensing device comprising more than two linearly oriented sensing components;

wherein said sensing device senses movement of the retro beam corresponding to anomalies on said specimen.